

ABSTRACT OF THE DISCLOSURE

A method of patterning a thin film includes a step of forming at least one strippable conductive film on a surface of a thin film to be patterned, a step of forming a mask on the at least one strippable conductive film, a step of patterning the thin film to be patterned by dry etching using the mask, and a step of removing the at least one strippable conductive film.